

US005711849A

## United States Patent [19]

Flamm et al.

5,711,849 **Patent Number:** [11] Date of Patent: [45]

Jan. 27, 1998

#### PROCESS OPTIMIZATION IN GAS PHASE [54] DRY ETCHING

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[21] Appl. No.: 433,623

[22] Filed: May 3, 1995

[51] Int. Cl.<sup>6</sup> ...... H01L 21/3065 [52] U.S. Cl. ...... 156/643.1; 156/625.1; 156/346 P; 156/626.1; 156/659.11; 156/646.1; 204/298.31; 204/298.32; 216/58; 216/59

216/39, 58, 74, 79, 246 P, 625.1, 643.1, 626.1, 646.1, 659.1, 662.1, 659.11

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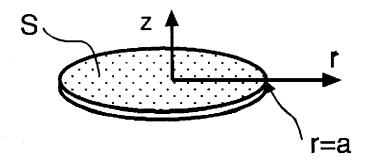
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Primary Examiner-Martin Angebranndt Attorney, Agent, or Firm-Townsend and Townsend and Crew LLP

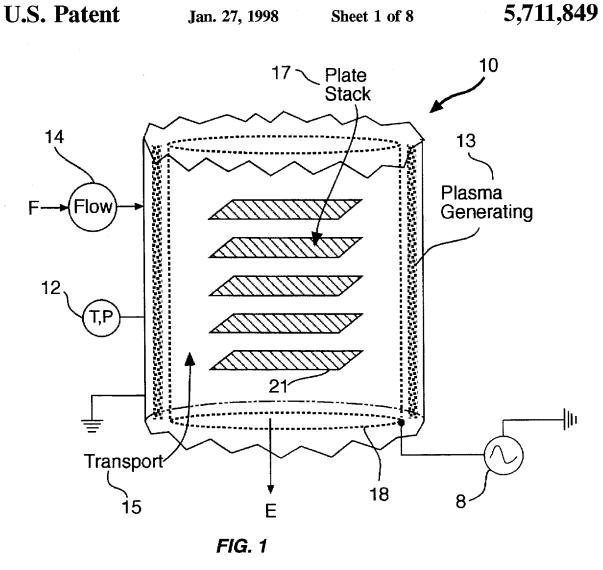
#### [57] ABSTRACT

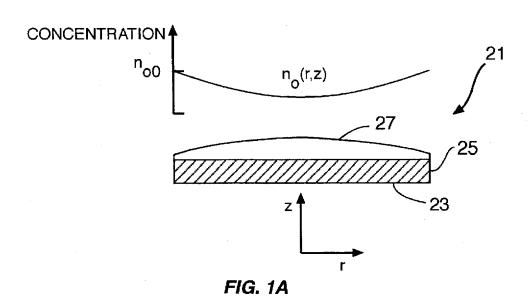
A method of designing a reactor 10. The present reactor design method includes steps of providing a first plasma etching apparatus 10 having a substrate 21 therein. The substrate includes a top surface and a film overlying the top surface, and the film having a top film surface. The present reactor design method also includes chemical etching the top film surface to define a profile 27 on the film, and defining etch rate data from the profile region. A step of extracting a reaction rate constant from the etch rate data, and a step of using the reaction rate constant in designing a second plasma etching apparatus is also included.

### 29 Claims, 8 Drawing Sheets

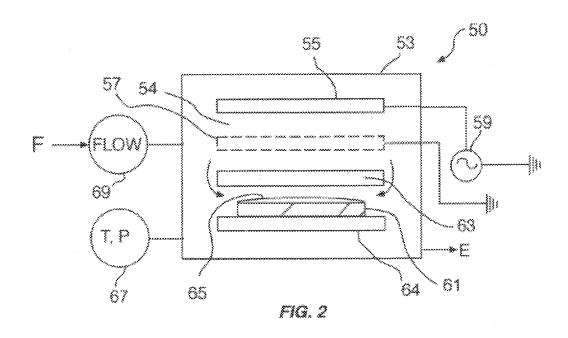


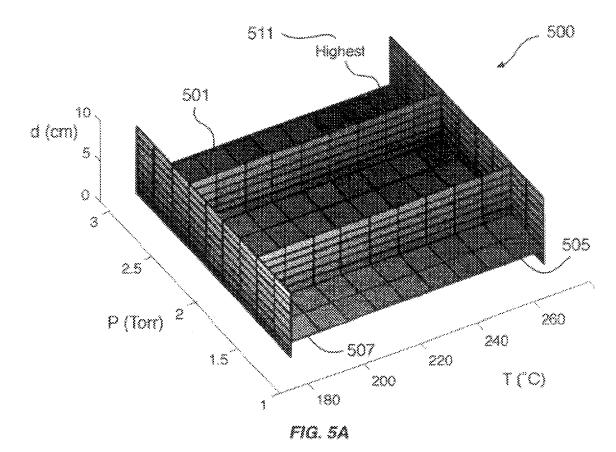














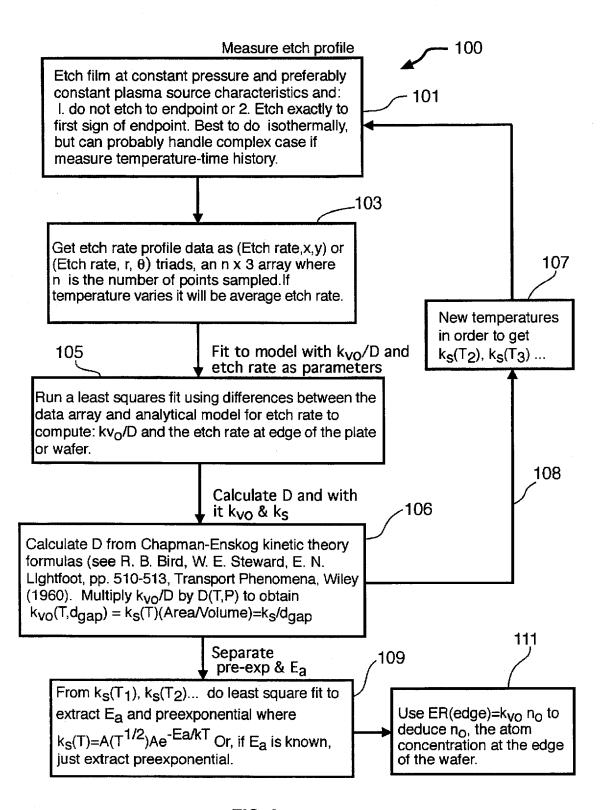


FIG. 3



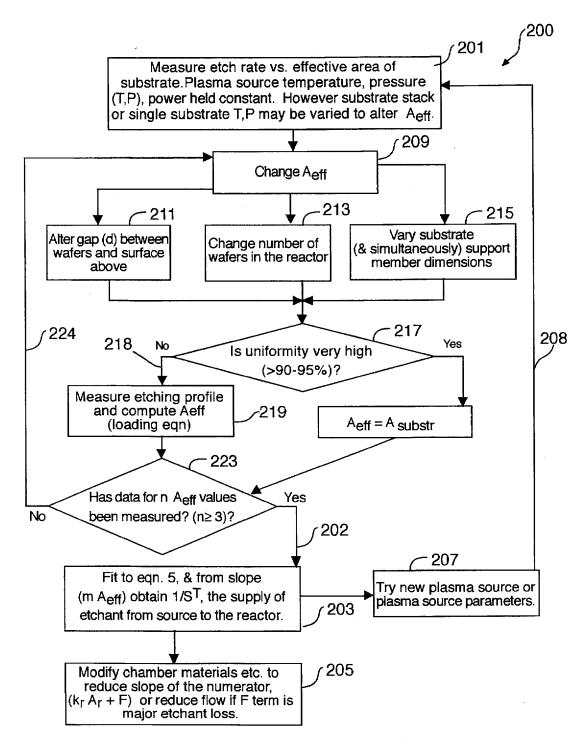


FIG. 4



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